



PATENT APPLICATION

IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tatsuo ITO et al.

ATTN: Application Branch

Application No.: 10/502,389

Docket No.: 120503

Filed: July 26, 2004

For: METHOD FOR MANUFACTURING SEMICONDUCTOR WAFER, METHOD
FOR RECEIVING ORDER FOR MANUFACTURE OF SEMICONDUCTOR
WAFER, AND SYSTEM FOR RECEIVING ORDER FOR MANUFACTURE OF
SEMICONDUCTOR WAFER

CORRECTED FILING RECEIPT STATUS REQUEST

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

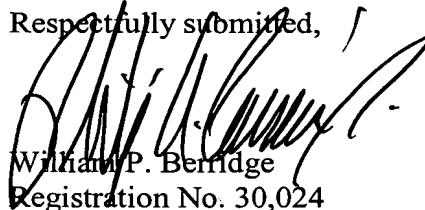
Sir:

A Request for Correction of PALM Records was filed on January 5, 2005. A copy of the postcard receipt is attached hereto. A copy of the Request for Correction of PALM Records is also attached.

The corrected Filing Receipt has not yet been received. It is respectfully requested that the corrected Filing Receipt be immediately forwarded to the attorneys of record at the address set forth below.

If there are any questions regarding this matter, please contact the undersigned at the telephone number set forth below.

Respectfully submitted,



William P. Berridge
Registration No. 30,024

Philip A. Caramanica, Jr.
Registration No. 51,528

WPB:PAC/cqc

Date: April 21, 2005

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400



PTO RECEIPT FOR FILING OF PAPERS

► Mail Room (Regular Delivery)

The following papers have been filed:

Request for Correction of PALM Records; Marked-up OFR

Name of Applicant: Tatsuo ITO et al.

Serial No.: 10/502,389

Atty. File No.: 120503

Title (New Cases):

Sender's Initials: JAO/cqc

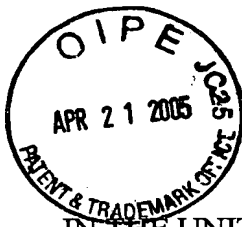
181/23

PATENT OFFICE DATE STAMP



**COPY TO BE STAMPED BY PATENT OFFICE
AND RETURNED BY MESSENGER**

**Oliff & Berridge, PLC
277 S. Washington Street, Suite 500, Alexandria, Virginia 22314**



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Tatsuo ITO et al.

Application No.: 10/502,389

Docket No.: 120503

Filed: July 26, 2004

For: METHOD FOR MANUFACTURING SEMICONDUCTOR WAFER, METHOD
FOR RECEIVING ORDER FOR MANUFACTURE OF SEMICONDUCTOR
WAFER, AND SYSTEM FOR RECEIVING ORDER FOR MANUFACTURE OF
SEMICONDUCTOR WAFER

REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Eric D. Morehouse
Registration No. 38,565

JAO:EDM/cqc

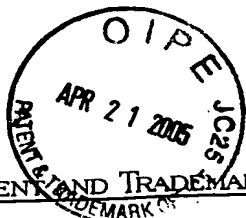
Date: January 5, 2005

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>



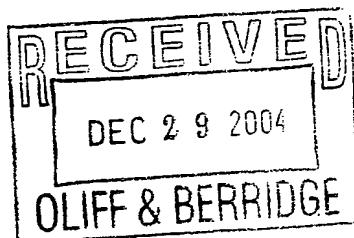
UNITED STATES PATENT AND TRADEMARK OFFICE



UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450
www.uspto.gov

APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/502,389	07/26/2004	2812	1190	120503	6	35	3

25944
OLIFF & BERRIDGE, PLC
P.O. BOX 19928
ALEXANDRIA, VA 22320



CONFIRMATION NO. 3456

FILING RECEIPT



OC000000014830077

Date Mailed: 12/28/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Tatsuo Ito, Tokyo, JAPAN;
Shigeyoshi Netsu, Fukushima, JAPAN;
Masashi Ichikawa, Fukushima, JAPAN;
Nobuhiro Ohara, Fukushima, JAPAN;

Power of Attorney:

Thomas Pardini-30411

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/00557 01/22/2003

Foreign Applications

JAPAN 200219334 01/29/2002

Projected Publication Date: 04/07/2005

Non-Publication Request: No

Early Publication Request: No

Next Page →

Title

~~Semiconductor wafer manufacturing method, semiconductor wafer manufacturing order acceptance method, and semiconductor wafer manufacturing order acceptance system~~

Preliminary Class
438

Method for Manufacturing Semiconductor Wafer, Method for Receiving Order for Manufacture of Semiconductor Wafer, and System for Receiving Order for Manufacture of Semiconductor Wafer

LICENSE FOR FOREIGN FILING UNDER

Title 35, United States Code, Section 184

Title 37, Code of Federal Regulations, 5.11 & 5.15

GRANTED

The applicant has been granted a license under 35 U.S.C. 184, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" followed by a date appears on this form. Such licenses are issued in all applications where the conditions for issuance of a license have been met, regardless of whether or not a license may be required as set forth in 37 CFR 5.15. The scope and limitations of this license are set forth in 37 CFR 5.15(a) unless an earlier license has been issued under 37 CFR 5.15(b). The license is subject to revocation upon written notification. The date indicated is the effective date of the license, unless an earlier license of similar scope has been granted under 37 CFR 5.13 or 5.14.

This license is to be retained by the licensee and may be used at any time on or after the effective date thereof unless it is revoked. This license is automatically transferred to any related applications(s) filed under 37 CFR 1.53(d). This license is not retroactive.

The grant of a license does not in any way lessen the responsibility of a licensee for the security of the subject matter as imposed by any Government contract or the provisions of existing laws relating to espionage and the national security or the export of technical data. Licensees should apprise themselves of current regulations especially with respect to certain countries, of other agencies, particularly the Office of Defense Trade Controls, Department of State (with respect to Arms, Munitions and Implements of War (22 CFR 121-128)); the Office of Export Administration, Department of Commerce (15 CFR 370.10 (j)); the Office of Foreign Assets Control, Department of Treasury (31 CFR Parts 500+) and the Department of Energy.

NOT GRANTED

No license under 35 U.S.C. 184 has been granted at this time, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" DOES NOT appear on this form. Applicant may still petition for a license under 37 CFR 5.12, if a license is desired before the expiration of 6 months from the filing date of the application. If 6 months has lapsed from the filing date of this application and the licensee has not received any indication of a secrecy order under 35 U.S.C. 181, the licensee may foreign file the application pursuant to 37 CFR 5.15(b).